Notice of Allowability	Application No.	Applicant(s)	
	10/816,980	YU, HO-YUAN	
	Examiner	Art Unit	
	Renee R. Berry	2818	
The MAILING DATE of this communication appeared All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RI of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in this app or other appropriate communication IGHTS. This application is subject to	blication. If not include will be mailed in due	ed course. THIS
1. This communication is responsive to <u>1/10/05</u> .			
2. The allowed claim(s) is/are 1-20.			
3. The drawings filed on <u>02 April 2004</u> are accepted by the Examiner.			
4.			
	5. Notice of Informal P 6. Interview Summary Paper No./Mail Dat 7. Examiner's Amendr 8. Examiner's Stateme 9. Other Other Others Patent Examiner	(PTO-413), te ment/Comment	
Technology Center 2800			

REASONS FOR ALLOWANCE

The following is an examiner's statement of reasons for allowance: There is no prior art of record that teaches or suggests a method for filling a trench by forming a layer of silicon dioxide on the bottom and on a portion of the wall of a trench and depositing a polysilicon fill on the surface of a layer of silicon dioxide and on the surface of the wall.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Renee R. Berry whose telephone number is (571) 272-1774. The examiner can normally be reached on M-F 9-5:30.

The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

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April 15, 2005

David Nelms

Supervisory Patent Examiner Technology Center 2800